

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

APR 1999

Applicant : Jigish D. Trivedi  
Serial No. : 08/915,658  
Filed : August 21, 1997  
Title : LOW RESISTANCE METAL SILICIDE LOCAL INTERCONNECTS AND  
METHOD OF MAKING  
Docket : MIO 024 PA  
Examiner : G. Peralta  
Art Unit : 2814

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on April 9, 1999.

Attorney

Reg. No. 29,001

**RESPONSE TO RESTRICTION REQUIREMENT**

This paper is being filed in response to the Office Action mailed March 23, 1999. In that Action, the Examiner required restriction between claims 1-30, directed to a process of making a semiconductor device and claims 31-40, directed to a semiconductor device. Applicant hereby elects to have product claims 31-40 examined on their merits. Applicant requests that the non-elected process claims be permitted to remain in the application to be re-joined with the elected claims should those claims be allowed. See, "Guidance on Treatment of Product and Process Claims," Commissioner's Notice dated February 28, 1996.

Respectfully submitted,  
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& SCHAEFF, LLP

By

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